

Robust Fulcrum-Type Wafer-Level Packaged MEMS Switches Utilizing Al-Ru-AlCu **Contacts Fabricated in a Commercial MEMS Foundry**



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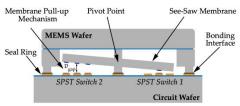
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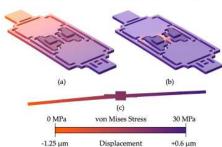
- From past two decades, advancements in RF MEMS switches have provide unique solutions to tunable devices.
- RF-MEMS usually suffer from reliability concerns including beam warping, contact degradation, high switching time and stiction.
- Hermetically sealed wafer level packaged devices are designed and fabricated to mitigate such concerns in a commercial MEMS foundry.
- Unique materials and thick silicon core for robust switching operation is demonstrated with exceptional RF performance.

NEW INSIGHTS

Redundancy Matrix using transfer switches.

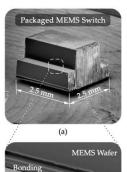
Fulcrum-type MEMS switches in hermetically wafer-level packaging.

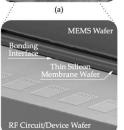




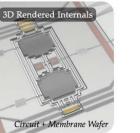
- Improved isolation and low insertion loss
- Stresses are minimized utilizing a thick silicon core structure.
- No electrical vias or passthroughs required.
- High switching speed and improved reliability due to the use of Al-Ru-AlCu contacts to minimize contact degradation
- 20 mask process with three wafers eutectic bonding.

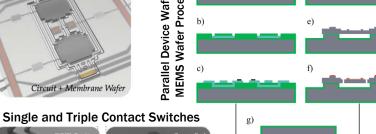
DESCRIPTION





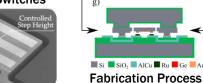




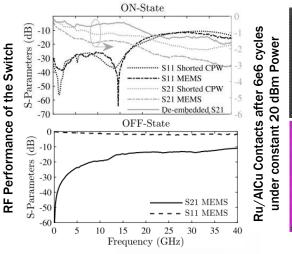


1.3 mm





QUANTITATIVE IMPACT





DC-14 GHz Insertion Loss < 0.2 dB Packaged Switch | Isolation > 20 dB

> 4e6 cycles

PROPOSED CONCEPT GOALS

- A highly reliable robust wafer level packaged RF MEMS switch.
- See-saw type mechanism that provides two unique and independent RF switches in a single hermetically sealed packaged (< 2.5 mm)
- Non-metallic thick silicon core to improve mechanical robustness.
- Au-Ru-AlCu metal contacts minimizes any micro-welding and contact degradation issues while silicon core provides warm free beams.
- Eutectic packaging approach to minimize any post release packaging issues and minimize any vibration related damages.



